* NOTICES *

JPO and NCIPI are not responsible for any damages caused by the use of this translation.

- 1. This document has been translated by computer. So the translation may not reflect the original precisely.
- 2.**** shows the word which can not be translated.
- 3.In the drawings, any words are not translated.

CLAIMS

[Claim(s)]

[Claim 1] The single crystal growth approach characterized by controlling the amount of heating of a heater so that the dissolution rate of this raw material pellet is in agreement with a speed of supply while supplying a raw material pellet according to the growth rate of a single crystal in being dropped in the crucible for single crystal growth, and carrying out single crystal growth, dissolving the supplied raw material pellet.

[Claim 2] The single crystal growth equipment which is equipped with the crucible for single crystal growth, the feeding cylinder which supplies a raw material pellet, and the crucible for dropping prepared in the lower limit of this feeding cylinder, carries out pendant support of said feeding cylinder through a load cell in the equipment into which a single crystal is grown up from a melting raw material, and is characterized by to form the control unit which controls the amount of heating of a heater so that the gravimetry value of this load cell turns into constant value.

[Translation done.]

* NOTICES *

JPO and NCIPI are not responsible for any damages caused by the use of this translation.

- 1. This document has been translated by computer. So the translation may not reflect the original precisely.
- 2.**** shows the word which can not be translated.
- 3.In the drawings, any words are not translated.

DETAILED DESCRIPTION

[Detailed Description of the Invention]

[0001]

[Industrial Application] This invention relates to the single crystal growth approach and equipment which use a Bridgman method etc. [0002]

[Description of the Prior Art] The single crystal growth equipment using a Bridgman method is equipment into which a melting raw material is contained, this is moved into the crucible for single crystal growth in the furnace which has a suitable temperature gradient, the melting raw material in a crucible is solidified gradually, and a single crystal is grown up. While controlling

single crystal growth in the furnace which has a suitable temperature gradient, the melting raw material in a crucible is solidified gradually, and a single crystal is grown up. While controlling coke oven temperature by such single crystal growth technique conventionally to set coke oven temperature as target temperature distribution, to measure the wall or ambient temperature of every place in a furnace, and to make such temperature in agreement with target temperature

distribution A solid-state raw material is contained in the crucible for single crystal growth, an elevated-temperature area is moved for this crucible, a raw material is dissolved, the constant-temperature area further maintained at coagulation temperature is moved, one direction solidification is carried out, and a single crystal is grown up.

[0003] With such a single crystal growth technique, the crystal growth side is very sensitive to change of temperature. Therefore, in the temperature control of a single crystal growth technique, though the furnace body of an electric furnace and the ambient atmosphere in an electric furnace were kept constant, by migration of the crucible for single crystal growth containing a crystal and melt, temperature fluctuation arises in respect of crystal growth, and the rate of crystal growth becomes an ununiformity. By the multicomponent system, the temperature fluctuation in respect of [this] crystal growth and especially fluctuation of the rate of crystal growth produce deflection in the presentation of solid phase and the liquid phase, and produce dispersion in the presentation of a single crystal. In such a crystal growth process, change of the temperature of a melting raw material changes the depth of a melting raw material.

[0004] In the approach of growing up a single crystal into JP,6–239689,A from a melting raw material to such a problem a) Supply a fine–particles raw material to a preparing–independently–raw material dissolution zone and single crystal growth zone b raw material dissolution zone by the shape of fine particles and a sintered compact, and it dissolves. The temperature of each melting raw material of a supplying–to single crystal growth zone–dissolved raw material c dissolution zone and a single crystal growth zone is measured, and performing crystal growth is indicated, controlling temperature independently in agreement with the setting presentation with those respectively fixed temperature, respectively. By separating a dissolution zone and a crystal growth zone and carrying out temperature control independently, respectively, this technique tends to eliminate a mutual interference, and it tends to control each temperature so that it becomes the optimal constant temperature and the depth of a melting raw material also becomes fixed.

[0005] Moreover, in the approach of growing up a single crystal into JP,6–239688,A from a melting raw material, a thermometer is inserted in the inside of a melting raw material, or right above, the temperature of the melting raw material near the solid–liquid interface or the skin temperature of a melting raw material is measured, and the single crystal growth approach of performing crystal growth is indicated, controlling a heater so that this measured value becomes fixed. This technique measures directly the temperature of the melting raw material made conventionally difficult, or the temperature of the front face of a melting raw material, and it controls it so that this temperature turns into constant temperature. Therefore, the effect of the disturbance which was not able to be removed can be removed completely, the temperature of a crystal growth side can be kept constant, and the temperature of a melting raw material can be controlled by the conventional means which keeps constant the temperature of the furnace near the crystal growth interface to the minimum temperature enough near solidification temperature. For this reason, the quality of a crystal produces operation that the single crystal of a fixed long picture can be manufactured well.

[0006]

[Problem(s) to be Solved by the Invention] However, it does not become a standard with the absolute temperature which a thermocouple displays since there is a problem which an impurity will mix or a training trouble will generate if the situation of dropping of a raw material is unknown in these techniques, and the dropping temperature of a raw material also changes with the location of a thermocouple or furnaces and a thermocouple is further put in into a melting raw material and temperature changes with locations inside the crucible for single crystal growth.

[0007] As mentioned above, the single crystal growth technique using the conventional Bridgman method controlled by the thermometry value cannot grasp the dropping condition of a raw material exactly, but the measured value of temperature is not clear in what is measured by the measuring point, and has problems, like the rate of crystal growth becomes an ununiformity by fluctuation by the measurement ambient atmosphere, fluctuation produced by migration of the location of the crucible for single crystal growth.

[0008] This invention adds an improvement to the approach of growing up a single crystal from a melting raw material, it performs single crystal growth continuously, supplying a raw material, and aims at offering the single crystal growth approach of manufacturing the single crystal of high quality with a sufficient yield, and its equipment.
[0009]

[Means for Solving the Problem] The technical means of the single crystal growth approach by which it is characterized [of this invention] is controlling the amount of heating of a heater so that the dissolution rate of this raw material pellet is in agreement with a speed of supply while supplying a raw material pellet according to the growth rate of a single crystal in being dropped in the crucible for single crystal growth, and carrying out single crystal growth, dissolving the supplied raw material pellet.

[0010] In this invention, it is the control approach which makes fundamentally not the temperature control by the measured value of a thermometer but the melting point of the dissolution raw material of an ingredient which carries out single crystal growth the parameter of internal temperature. That is, it is the control approach which sets constant the melting rate (raw material pellet holdup by the difference in in the display temperature of a heater thermocouple and the melting condition in a melting location) of a raw material pellet. As equipment of this invention which can carry out suitably, the above-mentioned approach In the equipment into which is equipped with the crucible for single crystal growth, the feeding cylinder which supplies a raw material pellet, and the crucible for dropping prepared in the lower limit of this feeding cylinder, and a single crystal is grown up from a melting raw material It is single crystal growth equipment which carries out pendant support of said feeding cylinder through a load cell, and is characterized by forming the control unit which controls the amount of heating of a heater so that the gravimetry value of this load cell turns into constant value. the raw material pellet with which the gravimetry value of a load cell was supplied -- the amount of survival of **** is sometimes shown. That is, it fuses with the amount of pellets supplied newly, and a difference with the dropped amount of raw materials serves as variation of measured value.

[0011] This equipment makes it a principle to perform control made into the parameter of internal temperature using the melting point of a dissolution raw material by making the holdup before the dissolution of feed regularity.

[0012]

[Embodiment of the Invention] With reference to a drawing, the gestalt of operation of this invention is explained below. <u>Drawing 3</u> is the whole single crystal growth equipment explanatory view in which this invention is applied. Single crystal growth equipment 1 is equipment into which the melting raw material 11 is contained, the inside of the furnace 30 which heated this at the heater 31 is caudad moved into the crucible 10 for single crystal growth, seed crystal is arranged to the lower limit of a crucible 10, and a single crystal 12 is grown up. A furnace 30 is divided into two or more blocks in the height direction, and can control the amount of heating independently, respectively.

[0013] The feeding cylinder 20 which supplies the raw material pellet 50 equipped the upper limit with the hopper 21, and equips the lower limit of a feeding cylinder with the crucible 22 for dropping. The amount of supply 23 of a raw material pellet is supplied so that it may be in agreement with a single crystal growth rate. The raw material pellet 50 which carries out sequential descent of the inside of the feeding cylinder 20 reaches the crucible 22 for dropping of a lower limit one by one, and trickles the fused raw material in the crucible 10 for single crystal growth.

[0014] It measured conventionally with the thermometer which carried out the illustration abbreviation of the temperature of every place of this equipment, and it was controlling so that that measured value was in agreement with desired value. Drawing 2 is made dropped in the crucible 10 for single crystal growth by using as the dropping raw material 51 the raw material which was the explanatory view of equipment conventionally which shows this, supplied the raw material pellet 50 to the feeding hopper 21, and was fused within the crucible 22 for dropping of the lower limit of the feeding cylinder 20, and makes the melting raw material 11 solidify as a

single crystal 12. Although illustration of a thermometer is omitted, the heater 31 is controlled by drawing 2 so that the measured value of a thermometer in each place becomes target temperature distribution. In this case, when heater temperature is high, there is a problem which an impurity mixes into a single crystal, and if heater temperature is low, a raw material will not dissolve and trickle. Moreover, there is a possibility that an impurity may mix into a single crystal, by inserting a thermometer.

[0015] Drawing 1 is the explanatory view of the feeding section of the single crystal growth equipment of the example of this invention. Pendant support of the feeding cylinder 20 is carried out through the load cell 2 and the pendant member 3. The feeding cylinder 20 is inserted into the furnace 30, and equips the lower limit with the dropping crucible 22. The raw material 51 fused from the dropping crucible 22 trickles. Through the pendant member 3, a load cell 2 is arranged on the center of gravity of a pendant object, raises the accuracy of measurement above a hopper 21, and secures the measuring power of 0.1g in it. The load cell 2 is attached in the frame which is not illustrated. Moreover, since the load cell 2 was arranged above the hopper 21 and has performed heat insulation processing (illustration abbreviation), heat insulation protection is easy for it. This load cell 2 measures correctly the weight of the raw material pellet which exists in the feeding cylinder 20 and the dropping crucible 22. Measured value, such as fluctuation of the weight of this raw material pellet, a fluctuation inclination, and abundance, is inputted into a control unit 40.

[0016] A control unit 40 carries out feedback control of the amount of heating of a heater 31 so that the gravimetry value of the inputted load cell 2 may become fixed. Usually, although the heaters 31 are three steps of heaters 31a, 31b, and 31c up and down, they are good to control heater 31b which influences the melting condition of a central dropping crucible. By this, by this invention, it can act as the monitor of the internal temperature using the melting point of a melting raw material, and the measured value of a load cell 2 can be used as a parameter of absolute temperature using the melting point regardless of fluctuation of the output by degradation of a heater 31, the temperature fluctuation by the difference in the location of a thermocouple, etc. Therefore, a yield can be good and the single crystal of high quality can be grown up stably.

[0017]

[Effect of the Invention] According to this invention, the place which internal temperature will be used as a parameter by controlling the amount of heating of a heater using the melting point of a raw material, and proper control can be performed regardless of the difference in a furnace or the situation of degradation and others of a heater so that the dissolution rate of this raw material pellet may be in agreement with a speed of supply, and contributes to the quality improvement and the improvement in a yield in a single crystal is size.

[0018] Moreover, since the control unit which carries out pendant support of the feeding cylinder which supplies a raw material pellet through a load cell, and controls the amount of heating of a heater by the gravimetry value of a load cell was formed according to this invention equipment, the above-mentioned this invention approach can be enforced suitably.

[Translation done.]

* NOTICES *

JPO and NCIPI are not responsible for any damages caused by the use of this translation.

- 1. This document has been translated by computer. So the translation may not reflect the original precisely.
- 2.**** shows the word which can not be translated.
- 3.In the drawings, any words are not translated.

DESCRIPTION OF DRAWINGS

[Brief Description of the Drawings]

[Drawing 1] It is the explanatory view of an example.

[Drawing 2] It is the explanatory view of the conventional example.

[Drawing 3] It is the whole single crystal growth equipment explanatory view.

[Description of Notations]

- 1 Single Crystal Growth Equipment
- 2 Load Cell
- 3 Pendant Member
- 10 Crucible for Single Crystal Growth
- 11 Melting Raw Material
- 12 Single Crystal
- 20 Feeding Cylinder
- 21 Hopper
- 22 Dropping Crucible
- 23 The Amount of Feeding
- 30 Furnace
- 31 (31a, 31b, 31c) Heater
- 32 Inside of Furnace
- 40 Control Unit
- 50 Raw Material Pellet
- 51 Dropping Raw Material

[Translation done.]

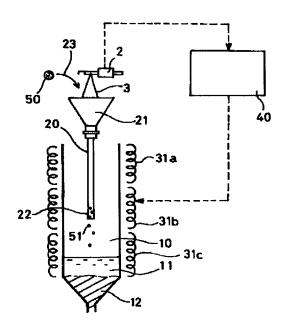
* NOTICES *

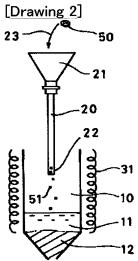
JPO and NCIPI are not responsible for any damages caused by the use of this translation.

- 1. This document has been translated by computer. So the translation may not reflect the original precisely.
- 2.**** shows the word which can not be translated.
- 3.In the drawings, any words are not translated.

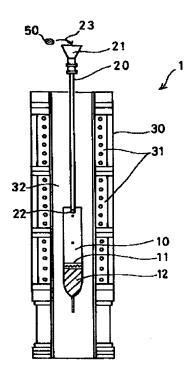
DRAWINGS

[Drawing 1]





[Drawing 3]



[Translation done.]

(19)日本国特許庁 (JP)

(12) 公開特許公報(A)

(11)特許出願公開番号

特開平11-1388

(43)公開日 平成11年(1999)1月6日

(51) Int.Cl.⁶

識別記号

FΙ

C30B 11/04

C30B 11/04

審査請求 未請求 請求項の数2 OL (全 4 頁)

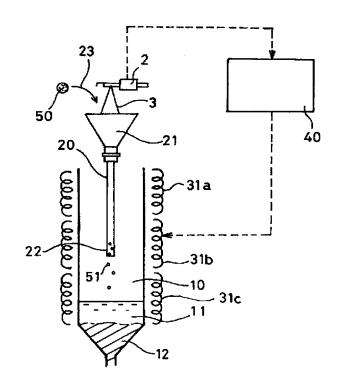
(21)出願番号	特願平9-152080	(71) 出願人 000200301
		川鉄鉱業株式会社
(22)出顧日	平成9年(1997)6月10日	東京都港区芝公園2丁目4番1号
		(72)発明者 舘 義仁
		東京都港区芝公園2丁目4番1号 川鉄鉱
		業株式会社内
		(72)発明者 越前谷 一彦
		東京都港区芝公園2丁目4番1号 川鉄鉱
		業株式会社内
		(74)代理人 弁理士 小杉 佳男 (外1名)

(54) 【発明の名称】 単結晶成長方法及び装置

(57)【要約】

【課題】ブリッジマン法等を用いる単結晶成長において、従来の温度測定値によって制御する技術の欠点を改善し、高品質の単結晶を歩留よく製造する。

【解決手段】原料供給筒20をロードセル2で吊下し、重量測定値を制御装置40に入力し、重量測定値が一定になるようにヒータ31の加熱量をフィードバック制御する。このことによって、温度を測定することなく、溶融原料の融点を利用して内部温度をモニターすることができ、ヒータの劣化による出力の変動、熱電対の位置の違いによる温度変動等に無関係に、高品質の単結晶を、歩留よく、安定的に成長させることができる。



1

【特許請求の範囲】

【請求項1】 供給した原料ペレットを溶解させながら 単結晶成長用ルツボ内に滴下して単結晶成長させるにあ たり、単結晶の成長速度に合わせて原料ペレットを供給 すると共に、該原料ペレットの溶解速度が供給速度と一 致するようにヒータの加熱量を制御することを特徴とす る単結晶成長方法。

【請求項2】 単結晶成長用ルツボと、原料ペレットを供給する原料供給筒と、該原料供給筒の下端に設けられた滴下用ルツボとを備え、溶融原料から単結晶を成長さ 10 せる装置において、前記原料供給筒をロードセルを介して吊下支持し、該ロードセルの重量測定値が一定値になるようにヒータの加熱量を制御する制御装置を設けたことを特徴とする単結晶成長装置。

【発明の詳細な説明】

[0001]

【産業上の利用分野】本発明は、ブリッジマン法等を用いる単結晶成長方法及び装置に関する。

[0002]

【従来の技術】ブリッジマン法を用いる単結晶成長装置 20 は、単結晶成長用ルツボ内に溶融原料を収納し、これを適当な温度勾配を有する炉内で移動させ、ルツボ内の溶融原料を徐々に固化させて単結晶を成長させる装置である。従来、このような単結晶成長技術では、炉温を目標温度分布に設定し、炉内各所の壁又は雰囲気温度を測定し、これらの温度を目標温度分布に一致させるように炉温を制御すると共に、固体原料を単結晶成長用ルツボ内に収納し、このルツボを高温区域を移動させて原料を溶解し、さらに凝固温度に保った一定温度区域を移動させて一方向固化させて単結晶を成長させるものである。 30

【0003】このような単結晶成長技術では、結晶成長面は温度の変化に対して非常に敏感である。従って、単結晶成長技術の温度制御においては、電気炉の炉体や電気炉内の雰囲気を一定に保っていたとしても、結晶及び融液の入った単結晶成長用ルツボの移動によって、結晶成長面では温度変動が生じ、結晶成長速度が不均一になる。この結晶成長面での温度変動や結晶成長速度の変動は、特に多成分系では、固相と液相の組成に偏差を生じ、単結晶の組成にばらつきを生じる。このような結晶成長過程において、溶融原料の温度が変化すると、溶融 40原料の深さが変化する。

【0004】とのような問題に対して、特開平6-23 9689には溶融原料から単結晶を成長させる方法において、

- a) 原料溶解ゾーンと単結晶成長ゾーンを別に設けるこ
- b) 原料溶解ゾーンに粉体原料を粉体及び焼結体状で供給して溶解し、溶解した原料を単結晶成長ゾーンに供給すること
- c)溶解ゾーンと単結晶成長ゾーンのそれぞれの溶融原 50

料の温度を測定し、それらの温度がそれぞれ一定の設定 組成に一致するようにそれぞれ独立に温度を制御しつつ 結晶成長を行うこと

が記載されている。との技術は溶解ゾーンと結晶成長ゾーンとを分離し、それぞれ独立に温度制御するととによって、相互の干渉を排除し、それぞれの温度を最適な一定温度になり、溶融原料の深さも一定になるように制御しようとするものである。

【0005】また、特開平6-239688号公報には 溶融原料から単結晶を成長させる方法において、溶融原 料中又は直上に温度計を挿入して固液界面近傍の溶融原 料の温度又は溶融原料の表面温度を測定し、この測定値 が一定になるようにヒータを制御しつつ結晶成長を行う 単結晶成長方法が開示されている。この技術は、従来困 難であるとされていた溶融原料の温度又は溶融原料の表 面の温度を直接測定し、この温度が一定温度になるよう に制御するものである。従って、結晶成長界面の近傍の 炉の温度を一定に保つ従来の手段では除去することがで きなかった外乱の影響を完全に除去することができ、結 晶成長面の温度を一定に保つことができ、溶融原料の温 度を固化温度に十分に近い最低の温度に制御することが できる。このため、結晶の品質が一定な長尺の単結晶を 能率よく製造することができるという作用を生じるもの である。

[0006]

【0008】本発明は、溶融原料から単結晶を成長させる方法に改善を加え、原料を供給しながら連続的に単結晶成長を行い、高品質の単結晶を歩留よく製造する単結晶成長方法及びその装置を提供することを目的とする。 【0009】

【課題を解決するための手段】本発明の特徴とする単結 晶成長方法の技術手段は、供給した原料ペレットを溶解 させながら単結晶成長用ルツボ内に滴下して単結晶成長 させるにあたり、単結晶の成長速度に合わせて原料ペレ ットを供給すると共に、該原料ペレットの溶解速度が供 給速度と一致するようにヒータの加熱量を制御すること

2

3

である。

【0010】本発明では、基本的に温度計の測定値によ る温度制御ではなく、単結晶成長させる材料の溶解原料 の融点を内部温度のパラメータとする制御方法である。 すなわち原料ペレットの溶融速度(溶融位置におけるヒ ータ熱電対の表示温度と溶融状態との差異による原料べ レット滯留量)を一定とする制御方法である。上記方法 を好適に実施をすることができる本発明の装置として は、単結晶成長用ルツボと、原料ペレットを供給する原 料供給筒と、この原料供給筒の下端に設けられた滴下用 10 ルツボとを備え、溶融原料から単結晶を成長させる装置 において、前記原料供給筒をロードセルを介して吊下支 持し、このロードセルの重量測定値が一定値になるよう にヒータの加熱量を制御する制御装置を設けたことを特 徴とする単結晶成長装置である。ロードセルの重量測定 値は、供給された原料ペレットの時々刻々の残存量を示 している。つまり、新規に供給されるペレット量と溶融 して滴下する原料量との差が測定値の変化量となる。

【0011】この装置は、供給原料の溶解前の滞留量を一定にすることによって、溶解原料の融点を用いて内部 20 温度のパラメータとする制御を行うことを原理とするものである。

[0.012]

【発明の実施の形態】以下図面を参照して本発明の実施の形態を説明する。図3は本発明の適用される単結晶成長装置の全体説明図である。単結晶成長装置1は、単結晶成長用ルツボ10内に溶融原料11を収納し、これをヒータ31によって加熱した炉30内を下方に移動させ、ルツボ10の下端に種結晶を配置して単結晶12を成長させる装置である。炉30は高さ方向に複数のブロ 30ックに分割され、それぞれ独立に加熱量の制御をすることができる。

【0013】原料ペレット50を供給する原料供給筒20はその上端にホッパ21を備え、原料供給筒の下端に滴下用ルツボ22を備えている。原料ペレットの供給量23は単結晶成長速度と一致するように供給される。原料供給筒20内を順次降下する原料ペレット50は順次下端の滴下用ルツボ22に達し、溶融した原料は単結晶成長用ルツボ10内に滴下する。

【0014】従来はこの装置の各所の温度を図示省略し 40 た温度計で測定し、その測定値が目標値と一致するように制御していた。図2はこれを示す従来装置の説明図で、原料供給ホッパ21に原料ベレット50を供給し原料供給筒20の下端の滴下用ルツボ22内で溶融した原料を滴下原料51として単結晶成長用ルツボ10内に滴下させ、溶融原料11を単結晶12として凝固させる。図2では、温度計の図示を省略してあるが、各所の温度計の測定値が目標温度分布になるように、ヒータ31を制御している。この場合、ヒータ温度が高いと不純物が単結晶中に混入する問題があり、ヒータ温度が低いと原 50

.

料が溶解せず滴下しない。また、温度計を挿入すること によって単結晶中に不純物が混入する恐れがある。

【0015】図1は本発明の実施例の単結晶成長装置の原料供給部の説明図である。原料供給筒20をロードセル2、吊下部材3を介して吊下支持している。原料供給筒20は、炉30内に挿入されておりその下端に滴下ルツボ22を備えている。滴下ルツボ22から溶融した原料51が滴下する。ロードセル2は吊下部材3を介してホッパ21の上方に、吊下物の重心上に配置し、測定精度を高め、測定分解能0.1グラムを確保する。ロードセル2はホッパ21の上方に配設し断熱処理(図示省略)を施しているので、断熱保護が容易である。とのロードセル2は、原料供給筒20内及び滴下ルツボ22内に存在する原料ペレットの重量を正確に測定する。との原料ペレットの重量の変動、変動傾向、存在量等の測定値は制御装置40に入力される。

【0016】制御装置40は入力されたロードセル2の重量測定値が一定になるようにヒータ31の加熱量をフィードバック制御する。通常、ヒータ31は、上下に3段のヒータ31a、31b、31cとなっているが、中央の滴下ルツボの溶融状態に影響するヒータ31bを制御するとよい。このことによって、本発明では溶融原料の融点を利用して内部温度をモニターすることができ、ヒータ31の劣化による出力の変動、熱電対の位置の違いによる温度変動等に無関係に、ロードセル2の測定値を融点を用いる絶対的温度のパラメータとして利用することができる。従って、高品質の単結晶を、歩留よく、安定的に成長させることができる。

0 [0017]

【発明の効果】本発明によれば、該原料ペレットの溶解 速度が供給速度と一致するようにヒータの加熱量を制御 することにより原料の融点を利用して内部温度をパラメ ータとして利用することとなり、炉の差異やヒータの劣 化その他の状況に無関係に適正な制御ができ、単結晶の 高品質化と歩留向上に寄与するところが大である。

【0018】また、本発明装置によれば、原料ペレットを供給する原料供給筒をロードセルを介して吊下支持し、ロードセルの重量測定値によりヒータの加熱量を制御する制御装置を設けたので、上記本発明方法を好適に実施することができる。

【図面の簡単な説明】

- 【図1】実施例の説明図である。
- 【図2】従来例の説明図である。
- 【図3】単結晶成長装置の全体説明図である。 【符号の説明】

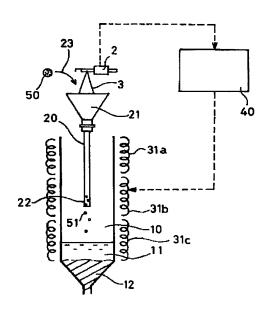
1 単結晶成長装置

- 2 ロードセル
- 3 吊下部材
- 0 10 単結晶成長用ルツボ

5

- 11 溶融原料
- 12 単結晶
- 20 原料供給筒
- 21 ホッパ
- 22 滴下ルツボ
- 23 原料供給量

【図1】



*30 炉

31 (31a, 31b, 31c) ヒータ

6

32 炉内

40 制御装置

50 原料ペレット

* 51 滴下原料

【図2】

【図3】

